

Supporting Information

An anisotropically crystallized and nitrogen-doped CuWO₄ photoanode for efficient and robust visible-light-driven water oxidation

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Table S1. Comparison of performances of state-of-the-art CuWO₄-based photoanodes for PEC water oxidation.^{a)}

Sample	Synthesis	Buffer	pH	$j_{1.23}$ / mA cm ⁻²	IPCE ₄₂₀ (%)	η_{sep} (%)	η_{cat} (%)	FE _{O₂} (%)	Stability: Remaining photocurrent (%) (reaction time)	Ref.
N-CuWO ₄	MiMIC	0.1 M KPi	7.0	0.21	5.6	12.3 ^{b)}	51.9 ^{b)}	97 ^{c)}	92 (40 h) ^{c)}	This work
CuWO ₄ nanoflake	Sacrificial templates	1.0 M KBi	9.5	0.4	8	12	55	nr	100 (5 h)	R1
CuWO ₄ nanoflake	Sacrificial templates	0.1 M KPi	7.0	0.3	nr	nr	nr	nr	95 (1 h)	R2
CuWO ₄ nanoflake	Sacrificial templates	0.2 M Na ₂ SO ₄	7.0	0.09	nr	10.8	15.8	nr	45 (6 h)	R3
CuWO ₄ with oxygen vacancy	Sacrificial templates	0.2 M Na ₂ SO ₄	7.0	0.2	nr	11.2	26.2	nr	60 (6 h)	R3
CuWO ₄	Ultrasonic spray pyrolysis	0.2 M Na ₂ SO ₄	6.4	0.033	nr	nr	nr	nr	96 (2100 s)	R4
CuWO ₄ on carbon nanotube	Spray pyrolysis	0.25 M (NaHCO ₃ /Na ₂ CO ₃)	10.0	0.23	7 ^{d)}	nr	nr	nr	85 (24 h) ^{d)}	R5
CuWO ₄	Spray pyrolysis	0.1 M KPi	7.0	0.13	< 1	2.5	25	nr	nr	R6
CuWO ₄	Spray pyrolysis	0.1 M KBi	7.0	0.08	nr	nr	nr	nr	nr	R7
CuWO ₄	Spin-coating	0.5 M KBi with 0.2M KCl	7.0	0.1	nr	nr	nr	nr	nr	R8
CuWO ₄	Spin-coating	0.1 M KPi	7.0	0.15	nr	nr	nr	100	15 (12 h)	R9
CuWO ₄	Spin-coating	0.1 M KBi	7.0	0.10	nr	nr	nr	96	93 (12 h)	R9
CuWO ₄	Spin-coating	0.1 M Na ₂ SO ₄	6.8	0.267	2	nr	nr	nr	nr	R10
Nodular CuWO ₄	Electrochemical deposition	0.1 M KPi	7.0	0.072	21 ^{e)}	nr	nr	> 90	nr	R11

CuWO_4	Electrochemical deposition	0.1 M KPi	7.0	0.026	0.2	nr	nr	nr	81 (150 s)	R12
CuWO_4 nanoparticle	Spray pyrolysis	0.1 M KPi	7.0	0.03	2	nr	nr	nr	50 (4000 s)	R13
CuWO_4	Spray pyrolysis	0.3 M KBi	7.5	0.027	0.03	nr	nr	nr	nr	R14
N_2 -treated CuWO_4	Electrochemical deposition	0.1 M KPi	7.0	0.08	nr	4	nr	nr	nr	R15
H_2 -treated CuWO_4	Hydrothermal	0.1 M Na_2SO_4	6.8	0.2	nr	nr	nr	nr	75 (1 h) ^{e)}	R16
CuWO_4 nanoparticle	Electrochemical deposition	0.1 M KPi	7.0	0.015	0.2	1.5	23	nr	nr	R17
Porous CuWO_4	Electrochemical deposition	0.1 M KPi	7.0	0.2	nr	nr	nr	nr	\sim 80 (12 h) ^{f)}	R18
CuWO_4 with a predominant (100) facet	Hydrothermal	0.2 M KPi	\sim 7	0.38	11	20.4	26.2	75	85 (6 h)	R19
Polycrystalline CuWO_4	RF magnetron sputtering	0.33 M H_3PO_4	1.35	0.126	nr	nr	nr	nr	nr	R20
CuWO_4	Spray pyrolysis	0.1 M KPi	7.0	0.5	nr	nr	nr	nr	\sim 80 (10 h)	R21

^{a)} nr: not reported, measured at 1.23V vs. RHE with simulated solar light (AM 1.5, 100 mW cm⁻²), ^{b)} monoclinic light (LED, 420 nm, 3.78 mW cm⁻²), ^{c)} visible light (Xe lamp with L39 and heat-cut filter, 100 mW cm⁻²), ^{d)} at 1.63 V vs. RHE, ^{e)} at 1.6 V vs. RHE, ^{f)} at 1.1 V vs. RHE.

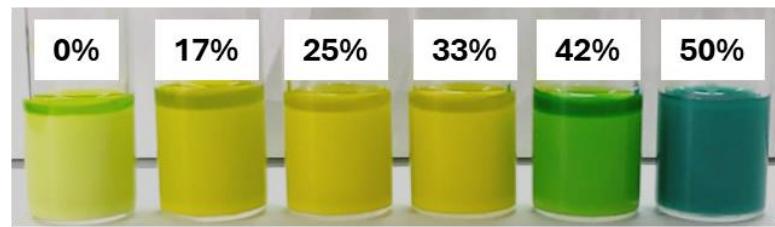


Figure S1 Photos of precursor suspensions containing 0.42 M $\text{Cu}(\text{NO}_3)_2$ and 0.50 M WCl_6 with different fractions ($F_{im} = 0 \sim 50\% \text{ vol}$) of BIm in methanol/BIm mixed solvents. F_{im} values are indicated on the figure.

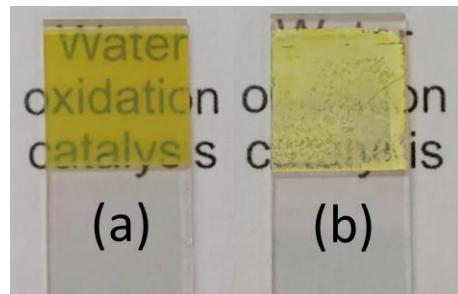


Figure S2 Photos of CuWO₄ films with F_{im} of (a) 33% and (b) 0% on an FTO substrate.

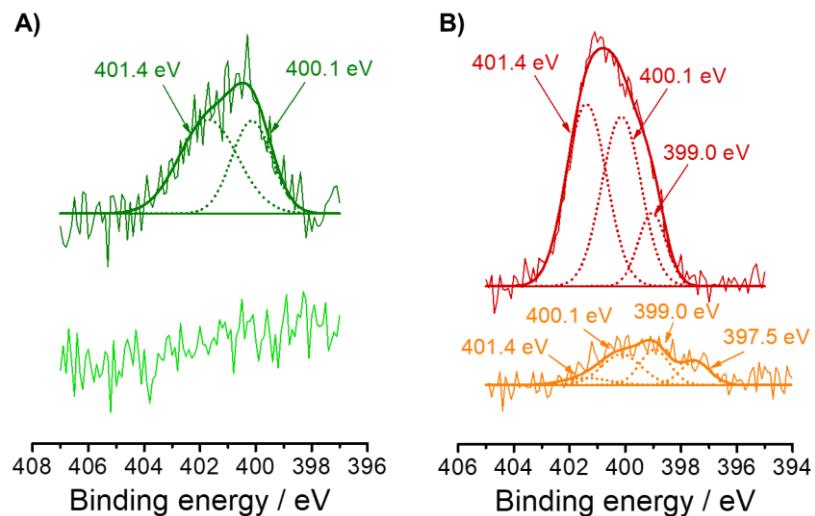


Figure S3. XPS spectra in the N1s region for CuWO₄ films with F_{im} of (A) 0% and (B) 33% before (top) and after (bottom) a surface treatment with Ar plasma etching.

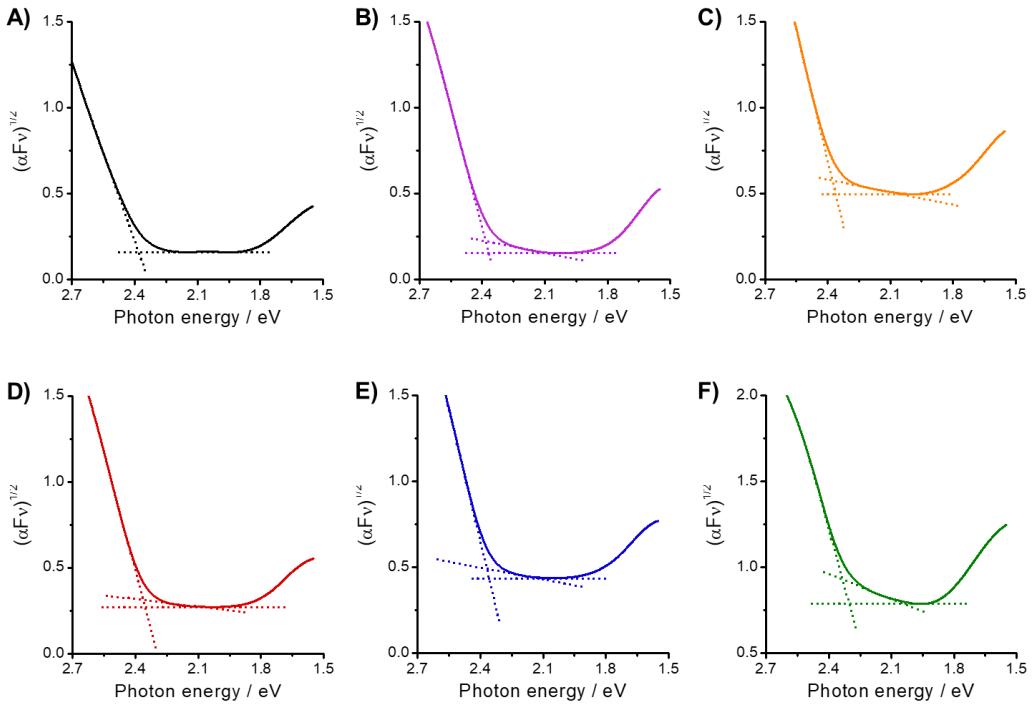


Figure S4 Tauc plots based on the DRS spectra (Figure 4A) of CuWO₄ films with F_{im} of (A) 0%, (B) 17%, (C) 25%, (D) 33%, (E) 42% and (F) 50%. The dotted lines represent slopes to calculate bandgap energies.

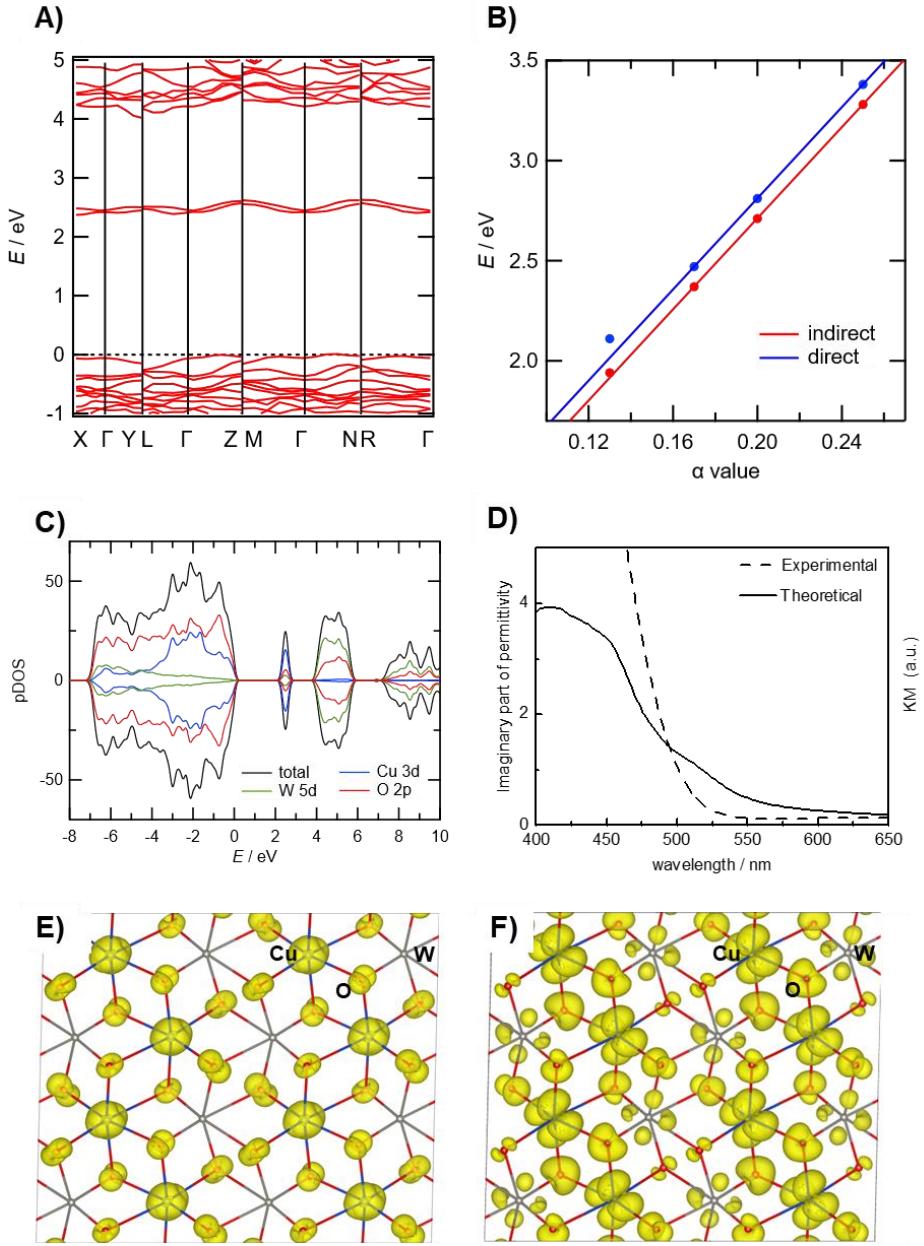


Figure S5 (A) Band diagram calculated for neat CuWO₄ crystals using HSE06 functional with the exact exchange mixing coefficient (α) of 0.17. (B) Plots of the calculated band gap versus α values. (C) pDOS diagram (black) calculated for neat CuWO₄ at $\alpha = 0.17$. Contributions from the Cu 3d (blue), O 2p (red) and W 5d (green) bands are indicated by different colors. (D) Imaginary part of the calculated dielectric coefficients (solid line) and the measured DRS spectrum for neat-CuWO₄ (dashed line). Integrated density of states (IDOS) of (E) the valence band (VB) top and (F) the conduction band (CB) bottom for neat CuWO₄. The atoms of Cu, O, and W are marked in figures.

Table S2. Parameters for calculation of replacement energies ($E_{\text{rep}}(\Delta\varepsilon_F)$) of O1-O4 with N^{1−}, N^{2−}, and N^{3−} for CuWO₄.

dopant	site	q	$E_{\text{rep}}(0)$
N ^{1−}	O1	+1	3.59
	O2	+1	3.83
	O3	+1	3.82
	O4	+1	3.69
N ^{2−}	O1	0	4.26
	O2	0	4.83
	O3	0	4.67
	O4	0	4.38
N ^{3−}	O1	-1	4.93
	O2	-1	5.35
	O3	-1	5.05
	O4	-1	5.18

Table S3. Summary of energy levels of VB top and CB bottom, impurity bands, and transition energies estimated from the PDOS diagrams.^a

Dopant	Site	Spin	E_{VB} / eV	E_{N-d} / eV	E_{N-a} / eV	E_{CB} / eV	Transition energy / eV (Assignment)
Neat		up	-0.42			1.95	2.37 (VB → CB)
		down	-0.42			1.95	2.37 (VB → CB)
N^{1-}	O1	up	0.00			2.25	2.25 (VB → CB)
			0.00		1.32		1.32 (VB → N-a1)
		down	0.00			2.33	2.33 (VB → CB)
			0.00		2.14		2.14 (VB → N-a2)
			0.00		1.47		1.47 (VB → N-a3)
N^{2-}	O2	up	0.00			2.23	2.23 (VB → CB)
		down	0.00			2.31	2.31 (VB → CB)
					1.97		1.97 (VB → N-a1)
					1.67		1.67 (VB → N-a2)
N^{2-}	O3	up	-0.14			2.10	2.24 (VB → CB)
				-0.03		2.10	2.13 (N-d1 → CB)
		down	-0.09			2.22	2.19 (VB → CB)
			-0.09		1.71		1.80 (VB → N-a1)
N^{2-}	O4	up	0.00			2.34	2.34 (VB → CB)
			0.00		2.21		2.21 (VB → N-a1)
			0.00		1.41		1.41 (VB → N-a2)
		down	0.00			2.32	2.32 (VB → CB)
			0.00		1.47		1.47 (VB → N-a1)
N^{2-}	O1	up	-0.29			2.00	2.30 (VB → CB)
				-0.01			2.02 (N-d1 → CB)
		down	-0.33			2.02	2.36 (VB → CB)
				-0.21		2.02	2.24 (N-d1 → CB)
			-0.33		1.86		2.19 (VB → N-a1)
	O2	up	-0.57			1.71	2.28 (VB → CB)
				-0.45		1.71	2.16 (N-d1 → CB)
		down	-0.57			1.68	2.25 (VB → CB)
			-0.57		1.38		1.95 (VB → N-a1)
				-0.10		1.68	1.78 (N-d1 → CB)
	O3	up	-0.42			1.85	1.68 (N-d2 → CB)
				-0.28		1.85	1.48 (N-d1 → N-a1)
		down	-0.44			1.85	1.38 (N-d2 → N-a2)
				-0.01	1.19		
			-0.44		1.19		1.63 (VB → N-a1)
				-0.01	1.19		1.20 (N-d1 → N-a1)
N^{2-}	O4	up	-0.20			2.12	2.32 (VB → CB)
				-0.02		2.12	2.14 (N-d1 → CB)
		down	-0.15	-		2.10	2.25 (VB → CB)

Table S3. (continued)

Dopant	Site	Spin	E_{VB}	E_{N-d}	E_{N-a}	E_{CB}	Transition energy (assignment)	
N^{3-}	O1	up	−0.59			1.73	2.32 ($VB \rightarrow CB$)	
				−0.43	1.73	2.16 ($N-d1 \rightarrow CB$)		
				−0.20	1.73	1.93 ($N-d2 \rightarrow CB$)		
				−0.09	1.73	1.82 ($N-d3 \rightarrow CB$)		
		down	−0.59			1.73	2.32 ($VB \rightarrow CB$)	
				−0.44	1.73	2.17 ($N-d1 \rightarrow CB$)		
				−0.01	1.73	1.74 ($N-d2 \rightarrow CB$)		
	O2	up	−0.53			1.79	2.32 ($VB \rightarrow CB$)	
				−0.31	1.79	2.10 ($N-d1 \rightarrow CB$)		
				−0.14	1.79	1.93 ($N-d2 \rightarrow CB$)		
		down	−0.50			1.74	2.24 ($VB \rightarrow CB$)	
				−0.18	1.74	1.92 ($N-d1 \rightarrow CB$)		
				−0.08	1.74	1.82 ($N-d2 \rightarrow CB$)		
				−0.01	1.74	1.75 ($N-d3 \rightarrow CB$)		
$O3$	up	up	−0.58			1.74	2.33 ($VB \rightarrow CB$)	
				−0.40	1.74	2.14 ($N-d1 \rightarrow CB$)		
				−0.31	1.74	2.05 ($N-d2 \rightarrow CB$)		
		down	−0.53			1.74	1.93 ($N-d3 \rightarrow CB$)	
				−0.19	1.74	2.28 ($VB \rightarrow CB$)		
				−0.18	1.74	1.92 ($N-d1 \rightarrow CB$)		
	down			−0.01	1.74	1.75 ($N-d2 \rightarrow CB$)		
				−0.52	1.73	2.26 ($VB \rightarrow CB$)		
				−0.32	1.73	2.05 ($N-d1 \rightarrow CB$)		
$O4$	up	up	−0.52			1.73	1.83 ($N-d2 \rightarrow CB$)	
				−0.09	1.73	2.24 ($VB \rightarrow CB$)		
				−0.01	1.73	1.73 ($N-d1 \rightarrow CB$)		

^{a)} E_{VB} , E_{VB} , E_{N-d} and E_{N-a} are energy levels of VB top, CB bottom, donor and acceptor impurity bands due to N 2p orbitals, respectively.

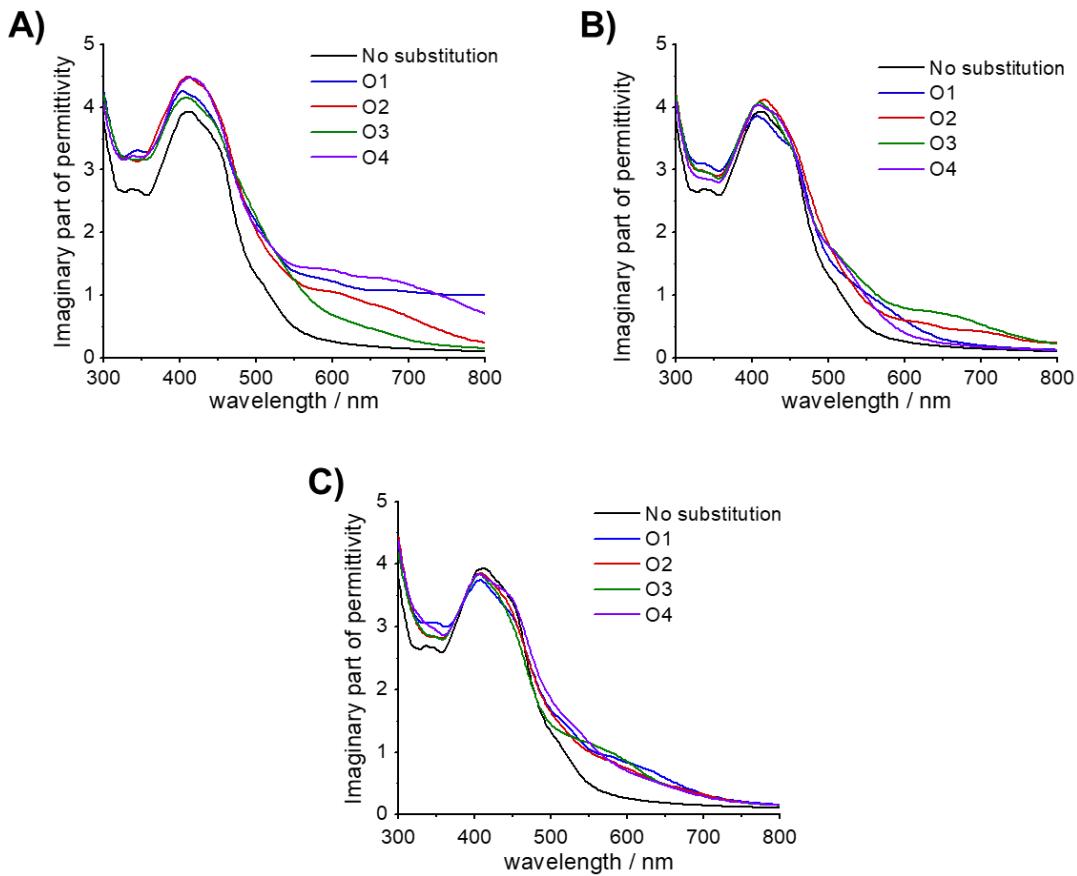


Figure S6. Imaginary part of the calculated dielectric coefficients for neat-CuWO₄ (black) and N-CuWO₄ with substitutions of O1-O4 with (A) N¹⁻, (B) N²⁻, and (C) N³⁻. The replaced O atoms in O1-O4 are indicated by different colors in each figure.

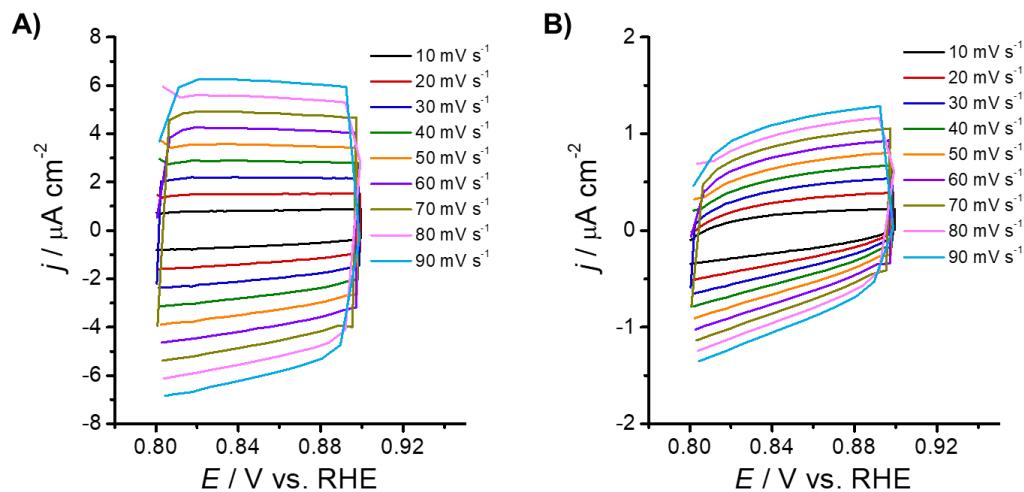


Figure S7 CVs of (A) N-CuWO₄ ($F_{\text{im}} = 33\%$) and (B) neat-CuWO₄ electrodes as measured in 0.1 M KPi solutions (pH = 7) in the potential range of 0.8 – 0.9 V vs. RHE at different scan rates of 10 – 90 mV s⁻¹ under dark conditions.

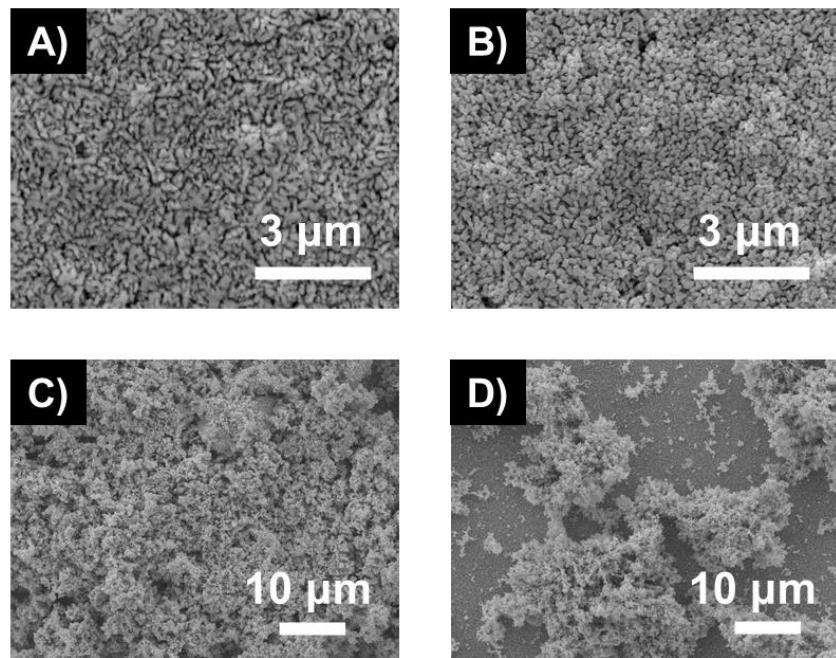


Figure S8 Top view SEM images of (A and B) N-CuWO₄ ($F_{im} = 33\%$) and (C and D) neat-CuWO₄ electrode (A and C) before and (B and D) after 15 h photoelectrolysis in a 0.1 M KPi buffer (pH 7.0) at 1.23 V under the light irradiation (>390 nm, 100 mW cm⁻²).

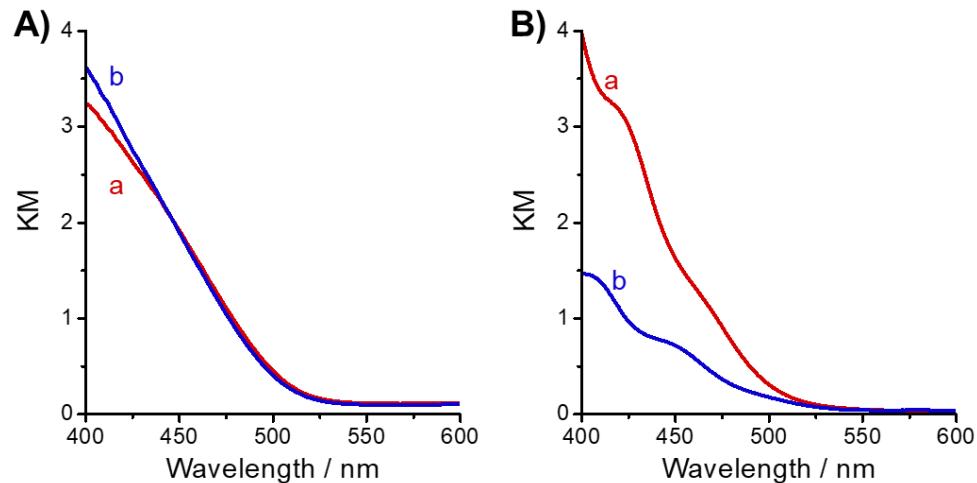


Figure S9 DRS of (A) N-CuWO₄ ($F_{im} = 33\%$) and (B) neat-CuWO₄ electrodes before (a, red) and after 15 h photoelectrolysis (b, blue) in a 0.1 M KPi buffer (pH 7.0) at 1.23 V under the light irradiation (>390 nm, 100 mW cm⁻²).

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